

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination	
		10/524,610	LAERMER ET AL.	
Examiner		Art Unit		Page 1 of 1
Hoang-Quan T. Ho		2818		

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,323,131	11-2001	Obeng et al.	438/687
*	B	US-2003/0013272	01-2003	Hong et al.	438/437
*	C	US-2006/0108576	05-2006	Laermer et al.	257/040
*	D	US-5,233,181	08-1993	Kwansnick et al.	250/208.1
*	E	US-2006/0068510	03-2006	Urban et al.	438/006
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	EP0822586	02-1998	Europe	Jeng, Shin-Puu	
	O	JP07-095306	11-1996	Japan	Kuwata Takaaki	
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Furuya et al. Fluorinated polyimide fabrication by magnetically controlled reactive ion etching (MC RIE). 1994. J. Micromech. Microeng. Vol. 4, pgs. 67-73.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.